EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	24768	((substrate or wafer) near4 (temperature or heat$3)) with (measur$5 or sens$3 or detect$3 or determin$5)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/08/26 12:20
L2	25407	(substrate or wafer) with (temperature or heat$3) with ((dimension$3 near response) or expan$4 or deform$5)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/08/26 12:21
L3	9934	(substrate or wafer) with (temperature or heat$3) with ((dimension$3 near response) or expan$4 or deform$5) with (calculat$3 or determin$5 or predict$3 or model$3 or coefficient)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/08/26 12:24
L4	886	1 and 3	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/08/26 12:25
L5	3848	(substrate or wafer) with ((dimension$3 near response) or expan$4 or deform$5) with (correct$3 or adjust$4 or compensat$3)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/08/26 12:26
L6	124	4 and 5	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/08/26 12:27
L7	186969	(mask or reticle or pattern$3) and ($6lithograph$3)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/08/26 12:28

L8	29	6 and 7	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/08/26 12:36

PK
8/26/06